

## Report of Scanning Electron Microscope (SEM) instruction

- Date and time : Monday, 5 August, 2019
  - (Morning) 10 : 30~12 : 00
  - (Afternoon) 13 : 00~14 : 30
  
- Location : At the Controlling of Nano- & Micro-Structures in Materials Laboratory No. 3 on the first floor of the material building in Faculty of Engineering
  
- Instructor : Assoc. Prof. Lee Seungwon  
Assist. Prof. Taiki Tsuchiya
  
- Contents : Method of using Scanning Electron Microscope (SEM)
  - Method of changing samples
  - Method of observationMethod of using Energy Dispersive X-ray Spectrometer (EDS)  
Method of using Electron Backscatter Diffraction (EBSD)
  
- Participants : (Morning) 7 people  
(Afternoon) 4 people
  
- Regarding this training:

We provided training on the basic operation of SEM and method of using EDS, EBSD this time. The participants showed great interests by asking us questions about the shapes and preparation of samples for observation.

